

Date: February 6, 2001

Page 1 of 1

Form PTO-1449 (REV. 8-83)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MEMSC-001XX	APPLICATION NO. 09/705,996 <b>RECEIVED</b>
		INFORMATION DISCLOSURE CITATION (Use several sheets if necessary)		MAY 8 - 2001	
				APPLICANT: Yang Zhao et al.	Technology Center 2100
				FILING DATE November 3, 2000	GROUP Not Assigned



## U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE*
SM	2,440,189	4/20/48	Zworykin			
SG	2,455,394	12/7/48	Webber			
CS	4,478,077	10/23/84	Bohrer et al.	73	204	
CG	4,542,650	9/24/85	Renken et al.	73	204	
BS	4,581,928	4/15/86	Johnson	73	204	
SG	4,637,253	1/20/87	Sekimura et al.	73	189	
CS	4,651,564	3/24/87	Johnson et al.	73	204	
BS	5,581,034	12/3/96	Dao et al.	73	514.09	
CS	5,719,333	2/17/98	Hosoi et al.	73	514.05	
SS	5,959,208	9/28/99	Muenzel et al.	73	514.32	

## FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES      NO

## OTHER DOCUMENTS (including Author, Title, Date, Pertinent Pages, Etc.)


EXAMINER	<i>[Signature]</i>	DATE CONSIDERED	<i>2/19/04</i>
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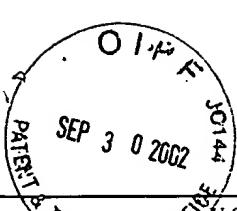
\*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Date: August 30, 2002  
Page 1 of 1

<b>U.S. DEPARTMENT OF COMMERCE</b> <b>PATENT AND TRADEMARK OFFICE</b> <small>(REV. 08/02)</small>				ATTY. DOCKET NO. MEMSC-001XX	APPLICATION NO. 09/705,996		
<b>INFORMATION DISCLOSURE CITATION</b> <i>(Use several sheets if necessary)</i>				APPLICANT: Yang Zhao et al.	<small>TECHNOLOGY CENTER 2800</small> <small>SEP 12 2002</small> <small>RECEIVED</small>		
				FILING DATE 11/3/00	GROUP 2811		
<b>U.S. PATENT DOCUMENTS</b>							
EXAMINER INITIAL	DOCUMENT NUMBER	PUBLICATION/ ISSUE DATE	NAME	CLASS	SUBCLASS	FILING DATE	
<i>g</i>	US6,171,880 B1	1/9/01	Gaitan et al.	438	52		
<i>m</i>	US5,581,034	12/3/96	Dao et al.	73	514.09		
	US						
	US					<b>RECEIVED</b>	
	US					SEP 18 2002	
	US					Technology Center 2100	
	US						
<b>FOREIGN PATENT DOCUMENTS</b>							
	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO
<b>OTHER DOCUMENTS</b> (including Author, Title, Date, Pertinent Pages, etc.)							
<i>on</i>	Freeform Fabrication of Functional Microsolenoids, Electromagnets and Helical Springs Using High-Pressure Laser Chemical Vapor Deposition, K. Williams, et al., pp. 232-237						
<i>g</i>	Micromachined Accelerometer Based On Convection Heat Transfer, A.M. Leung, et al., 0-7803-4412-X/98, 1998 IEEE, pp. 627-630						
<i>n</i>	Convection-based Accelerometer and Tilt Sensor Implemented in Standard CMOS, Veljko Milanovi, et al, International Mechanical Engineering Conference and Exposition, MEMS Symposia, Anaheim, CA, Nov. 18, 1998.						
EXAMINER				DATE CONSIDERED <i>2/19/04</i>			
<small>*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</small>							

\*Previously cited and considered on IDS filed 2/9/01

Date: September 24, 2002  
Page 1 of 1



<b>U.S. DEPARTMENT OF COMMERCE</b> <b>PATENT AND TRADEMARK OFFICE</b> <small>(REV. 08/02)</small>				ATTY. DOCKET NO. MEMSC-001XX	APPLICATION NO. 09/705,996		
<b>INFORMATION DISCLOSURE CITATION</b> <i>(Use several sheets if necessary)</i>				APPLICANT: Yang Zhao et al.	RECEIVED OCT -3 2002 C 2800 MAIL ROOM		
				FILING DATE 11/3/00	GROUP 2811		
<b>U.S. PATENT DOCUMENTS</b>							
EXAMINER INITIAL	DOCUMENT NUMBER	PUBLICATION/ ISSUE DATE	NAME	CLASS	SUBCLASS	FILING DATE	
	US						
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<b>FOREIGN PATENT DOCUMENTS</b>							
	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATIO N YES      NO	
<b>OTHER DOCUMENTS</b> (including Author, Title, Date, Pertinent Pages, etc.)							
<i>sm</i>	My Work on MEMS, Christian Zincke, 9/27/99, pp. 1-55						
<b>EXAMINER</b>	<i>sm</i>			<b>DATE CONSIDERED</b> <i>2/19/04</i>			
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